AF/ FRW

Docket No. <u>TIP477US</u>

TI-33260

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

e PATENT application of:

Applicant:

Patricia B. Smith et al.

Application No.:

10/647,985

For:

POST-ETCH CLEAN PROCESS FOR POROUS LOW

DIELECTRIC CONSTANT MATERIALS

Filing Date:

August 28, 2003

Examiner:

Zeinab El Arini

Art Unit:

1746

Enter 3/14/06

## **RESPONSE TO OFFICE ACTION DATED DECEMBER 29, 2005**

Mail Stop AF Assistant Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

Favorable reconsideration of the above-identified application is respectfully requested in view of the following amendments and remarks.